## Response to Final Office Action of September 4, 2009

## AMENDMENTS TO THE CLAIMS

Without prejudice, please amend claims 1, 2, 5, 6, and 9-14, so that the claims read as follows:

1. (Currently Amended) A stereolithographic method for forming a stereolithographic three-dimensional object by sequentially repeating, until a predetermined stereolithographic three-dimensional object is formed, optical building processes of exposing a surface of a photocurable resin composition layer by way of a planar plotting mask to thus form an optically-cured resin layer having a predetermined cross-sectional profile pattern; applying a photocurable resin composition layer over the optically-cured resin layer; and exposing the surface of the photocurable resin composition layer to light by way of the planar plotting mask, to thus further form an optically-cured resin layer having a predetermined cross-sectional profile pattern, the method comprising:

using a planar plotting mask, which can continuously change a mask image, as the planar plotting mask;

performing a building operation of continuously moving the planar plotting mask <u>over</u> <u>plotted areas with reference toon</u> the surface of the photocurable resin composition <u>layer such</u> that overlaps are formed between adjacent ones of the plotted areas during at least one of the optical building processes and of exposing the surface of [[a]]the photocurable resin composition <u>layer</u> to light by way of the planar plotting mask while continuously changing a mask image of the planar plotting mask in accordance with a cross-sectional profile pattern of an optically-cured resin layer to be formed and in synchronism with movement of the planar plotting mask, to thus form an optically-cured resin layer having a predetermined cross-sectional profile pattern; and

performing the optical building processes such that a computer is utilized to generate mask images to attenuate a visual noticeability of boundary areas the overlaps between among the adjacent plotted areas in the optically-cured resin layer in a finally-obtained stereolithographic three-dimensional object.

- 2. (Currently Amended) The stereolithographic method according to claim 1, wherein, in order to attenuate a visual noticeability of the <u>overlapsboundary areas</u> between the adjacent plotted areas in the optically-cured resin layer in a finally-obtained stereolithographic three-dimensional object, at least one operation selected from the group consisting of operations (i) to (iii) provided below is performed:
- (i) operation for making a total intensity of light radiated onto <u>overlaps betweenboundary</u> areas among adjacent plotted areas in an optically-cured resin layer equal or analogous to the intensity of light radiated onto areas other than the overlapsboundary areas;
- (ii) operation for making a shape of the <u>overlaps boundaries</u> between the adjacent plotted areas in the optically-cured resin layer curved; and
- (iii) operation for staggering positions of the <u>overlaps between boundary areas among</u> the adjacent plotted areas in the optically-cured resin layer in vertically-stacked optically-cured resin layers.
- 3. (Previously Presented) The stereolithographic method according to claim 1, wherein the planar plotting mask is a planar plotting mask in which a plurality of micro-optical shutters capable of blocking or allowing transmission of light into microdot areas are arranged in a planar manner; and

the surface of the photocurable resin composition is exposed to light while a mask image is continuously changed in accordance with a cross-sectional profile pattern to be formed by means of the plurality of micro-optical shutters during continuous movement of the planar plotting mask.

- 4. (Original) The stereolithographic method according to claim 3, wherein the planar plotting mask is a planar plotting mask where a liquid-crystal shutter or a digital micromirror shutter is arranged in a planar manner.
  - 5. (Currently Amended) A stereolithographic apparatus comprising:

a photocurable resin composition supply means for sequentially supplying a photocurable resin composition layer over a mount table or an optically-cured resin layer;

a light source;

a planar plotting mask capable of continuously changing a mask image, the stereolithographic apparatus being configured to continuously move the planar plotting mask over plotted areas with respect to on a surface of the photocurable resin composition layer such that overlaps are formed between adjacent ones of the plotted areas; and

a computer containing information for continuously changing the mask image of the planar plotting mask in synchronism with movement of the planar plotting mask, wherein

the apparatus is configured to generate mask images with the computer to attenuate a visual noticeability of boundary areas the overlaps among the adjacent plotted areas of optically-cured resin layers within a finally-obtained stereolithographic three-dimensional object.

- 6. (Currently Amended) The stereolithographic apparatus according to claim 5, wherein the apparatus is configured to attenuate the visual noticeability of the <u>overlapsboundary areas</u> by being configured to perform at least one operation selected from the group consisting of operations (i) to (iii) provided below:
- (i) operation for making a total intensity of light radiated onto the overlaps
   betweenboundary areas among adjacent plotted areas in an optically-cured resin layer equal or analogous to the intensity of light radiated onto areas other than the overlaps boundary areas;
- (ii) operation for making a shape of the <u>overlaps</u>boundaries between the adjacent plotted areas in the optically-cured resin layer curved; and
- (iii) operation for staggering positions of the <u>overlaps betweenboundary areas among</u> the adjacent plotted areas in the optically-cured resin layer in vertically-stacked optically-cured resin layers.
- (Previously Presented) The stereolithographic apparatus according to claim 5, wherein
  the planar plotting mask is a planar plotting mask in which a plurality of micro-optical shutters

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capable of blocking or allowing transmission of light into microdot areas are arranged in a planar

- (Previously Presented) The stereolithographic apparatus according to claim 5, wherein
  the planar plotting mask is a planar plotting mask where a liquid- crystal shutter or a digital
  micromirror shutter is arranged in a planar manner.
- 9. (Currently Amended) The stereolithographic apparatus according to claim 5, further comprising a light-condensing lens which is interposed between a <u>the</u> light source and the planar plotting mask and can be continuously moved in synchronism with the planar plotting mask; and a projection lens which is interposed between the planar plotting mask and the surface of the photocurable resin composition and which can be continuously moved in synchronism with the planar plotting mask.
- 10. (Currently Amended) The stereolithographic method according to claim 1, wherein the attenuation of the visual noticeability of the <u>overlapsboundary areas</u> between the adjacent plotted areas in the optically cured resin layer in a finally-obtained stereolithographic three-dimensional object results in the overlapsboundary areas being unnoticeable to the human eve.
- 11. (Currently Amended) The stereolithographic method according to claim 1, wherein, in order to attenuate a visual noticeability of the <u>overlapsboundary areas</u> between the adjacent plotted areas in the optically-cured resin layer in a finally-obtained stereolithographic three-dimensional object, an operation is performed for making a total intensity of light radiated onto <u>overlaps between boundary areas among</u> adjacent plotted areas in an optically-cured resin layer equal or analogous to the intensity of light radiated onto areas other than the <u>overlapsboundary</u> areas.
- 12. (Currently Amended) The stereolithographic method according to claim 1, wherein, in order to attenuate a visual noticeability of the <u>overlapsboundary areas</u> between the adjacent

plotted areas in the optically-cured resin layer in a finally-obtained stereolithographic threedimensional object, an operation is performed for making a shape of the <u>overlaps</u>boundaries between the adjacent plotted areas in the optically-cured resin layer curved.

- 13. (Currently Amended) The stereolithographic method according to claim 1, wherein, in order to attenuate a visual noticeability of the boundary areas overlaps between the adjacent plotted areas in the optically-cured resin layer in a finally-obtained stereolithographic three-dimensional object, an operation is performed staggering positions of the overlaps betweenboundary areas among the adjacent plotted areas in the optically-cured resin layer in vertically-stacked optically-cured resin layers.
- 14. (Currently Amended) The stereolithographic apparatus according to claim 5, wherein the apparatus is configured for the attenuation of the visual noticeability of the <u>overlaps</u> <u>betweenboundary areas among</u> the adjacent plotted areas in the optically cured resin layer in a finally-obtained stereolithographic three-dimensional object such that the <u>overlapsboundary</u> areas are unnoticeable to the human eve.